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## Magnetoresistance of $La_{1-x}Sr_xMnO_3$ films deposited by RF magnetron co-sputtering

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## Abstract

La–Sr–Mn–O thin films have been grown on  $SiO_2/Si(100)$  and MgO(100) substrate by co-sputtering LSMO compound target and pure Sr target. The La–Sr–Mn–O films deposited on MgO were grown to single phase, while the films grown on  $SiO_2/Si$  showed polycrystalline structure. The Sr ratio x of the deposited  $La_{1-x}Sr_xMnO_3$  films could be controlled in the range of 0.15 and 0.23 by varying the RF power to the Sr target. For the films on MgO(100), metal–insulator transition occurred at 270 K for x=0.15 and transition temperature increased as the Sr ratio increased. The MR curves showed sharp peaks at a temperature slightly lower than  $T_{M-1}$ . The maximum MR reached about 46.4% at 250 K for 1.5 T. For the films on  $SiO_2$ , the MR decreased monotonically, and films did not show any Sr ratio dependent electrical property differences. © 2001 Published by Elsevier Science B.V.

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